

UNITED STATES PATENT APPLICATION FOR:

DYNAMIC MEMORY CELL

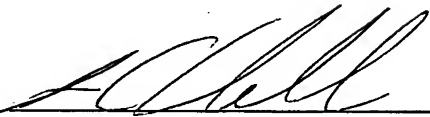
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DYNAMIC MEMORY CELL

CROSS-REFERENCE TO RELATED APPLICATIONS

[0001] This application claims foreign priority benefits under 35 U.S.C. §119 to co-pending German patent application 102 55 203.7-53, filed November 27, 2002. This related patent application is herein incorporated by reference.

BACKGROUND OF THE INVENTION

Field of the Invention

[0002] The invention relates to a dynamic memory cell for use in a DRAM memory.

Description of the Related Art

[0003] DRAM memory cells known hitherto have the disadvantage that only the potential of one bit line of a bit line pair is altered during an activation in the time in which the cell charge flows onto the bit line. The potential difference on the bit lines of the bit line pair is amplified by a sense amplifier, in which the potential with the higher charge is increased and the potential with the lower charge is decreased. The divergent separation of the charges on the bit lines of the bit line pair is not completely symmetrical since, proceeding from a center potential, only one of the bit lines is connected to the storage capacitor, so that initially only the charge of one bit line changes during the read-out of the memory cell. This leads to an asymmetrical divergent separation of the charges during amplification (presensing).

[0004] This behavior during presensing has the effect that it is not possible to completely preclude the signal coupling between adjacent bit lines of different adjacent bit line pairs with a twisting of the bit lines of the bit line pairs. By contrast the negative influences from the coupling between the bit lines can be virtually precluded with the aid of the twisting of the bit lines in the case of a symmetrical behavior in the case of charge separation in presensing.

SUMMARY OF THE INVENTION

[0005] It is an object of the present invention to provide a DRAM memory cell which makes it possible to reduce the negative coupling between the bit lines.

[0006] A first aspect of the present invention provides a dynamic memory cell which can be selected by means of a selection signal and the content of which can be read out by means of a bit line pair with a first and a second bit line. The dynamic memory cell has a storage capacitor connected to a first and a second selection transistor. Depending on the selection signal, the first terminal of the storage capacitor is connected to the first bit line via the first selection transistor and a second terminal of the storage capacitor is connected to the second bit line via the second selection transistor.

[0007] In this way, it is possible to provide a dynamic memory cell in which the charge content of the storage capacitor is applied to both bit lines of a bit line pair during the read-out. Prior to the read-out, the bit lines of the bit line pair are at an identical center potential brought about by a charge equalization carried out previously. As a result, in the event of simultaneous interposition of the capacitor between the bit lines of the bit line pair, the charge of one of the bit lines is reduced and the charge of the other bit line is increased by the same amount.

[0008] In this way, during the read-out of a memory cell, a signal profile which is essentially exactly the opposite, i.e. symmetrical, is achieved on the two bit lines. Thus, a bit line of a bit line pair which is essentially twisted in the center causes the opposite symmetrical signal profiles to be coupled in onto an untwisted adjacent bit line, so that the coupled-in signals reciprocally compensate one another.

[0009] It may be provided that the memory cell is constructed in a manner integrated in a substrate. The storage capacitor comprises a trench capacitor, an inner region being isolated from an outer region of the storage capacitor by an insulation layer in order to form a capacitor. The first selection transistor is connected to the inner

region of the storage capacitor and the second selection transistor is connected to the outer region of the storage capacitor, so that, in the event of the selection transistors being activated, the charge of the inner region is applied to the first bit line and the charge of the outer region is applied to the second bit line.

[0010] Preferably, for this purpose, the first and second selection transistors are arranged vertically on both sides of the trench capacitor. By virtue of the vertical arrangement of the selection transistors, the area requirement for the realization of such a memory cell remains very small, so that a DRAM memory having such dynamic memory cells is not significantly enlarged compared with a conventional DRAM memory.

[0011] In order to realize the vertically arranged selection transistors, a drive region, to which the drive signal is applied, may be arranged above the trench capacitor. The drive region is preferably configured in such a way that it may simultaneously serve as a gate region for the first and the second selection transistors.

[0012] The drain/source regions of the selection transistors are arranged at the trench capacitor in such a way that the trench capacitor is contact-connected. In this case, the drain/source region of the first selection transistor makes contact with the outer region of the storage capacitor and the drain/source region of the second selection transistor makes contact with the inner region of the storage capacitor. The respective further drain/source regions of the selection transistors are arranged near the surface in order to contact-connect them to the corresponding bit lines onto which the stored charge is to be read out.

BRIEF DESCRIPTION OF THE DRAWINGS

[0013] Preferred embodiments of the invention are explained in more detail below with reference to the accompanying drawings, in which:

[0014] Figure 1 shows an electrical diagram with components of a dynamic memory cell in accordance with a preferred embodiment of the invention;

[0015] Figure 2 shows a detail from a DRAM memory with memory cells in accordance with an embodiment of the invention with twisted bit lines;

[0016] Figure 3 shows a cross section through a substrate with an integrated dynamic memory cell according to the invention; and

[0017] Figure 4 shows a plan view of the substrate wafer with dynamic memory cells according to the invention.

DETAILED DESCRIPTION OF THE PREFERRED EMBODIMENT

[0018] Figure 1 illustrates a dynamic memory cell according to the invention. The memory cell has a storage capacitor C, the first terminal of which is connected to a first bit line BL1 of a bit line BLP via a first selection transistor T1. A second terminal of the storage capacitor C is connected to a second bit line BL2 of the bit line pair BLP via a second selection transistor T2. Control terminals of the first selection transistor T1 and of the second selection transistor T2 can be driven via a word line WL. The selection transistors T1, T2 are preferably designed as n-channel field-effect transistors, so that the selection transistors T1, T2 are turned on in the event of a HIGH potential on the word line WL.

[0019] If the selection transistors are in the on state, then the charge stored in the storage capacitor C flows equally onto the first bit line BL1 and the second bit line BL2. The two bit lines BL1, BL2 of the bit line pair BLP have previously been equalized to a center potential by means of a charge equalizing device (not shown).

[0020] The first bit line BL1 and the second bit line BL2 of the bit line pair BLP are connected to a sense amplifier 1 at one end. The sense amplifier is configured in such a way that it detects a charge difference between the two bit lines BL1, BL2

of the bit line pair BLP and increases the potential of the bit line with the higher charge and decreases the potential of the bit line with the lower charge. By virtue of the fact that the charge stored in the storage capacitor is applied to both bit lines equally and simultaneously, the result is a symmetrical opposite signal profile around the center potential on the two bit lines.

[0021] Furthermore, such a memory cell has the advantage that the two bit lines BL1, BL2 of a bit line pair BLP then have the same capacitance upon connection to the memory cell. Asymmetries resulting from the fact that the storage capacitor is applied only into one of the bit lines can thus be avoided.

[0022] Moreover, the magnitude of the signal between the bit lines BL1, BL2 of the bit line pair BLP is doubled. This could be utilized either to improve the signal properties and thus make the chip more reliable or else to reduce the power consumption by, e.g., halving the center potential. This results in a further advantage, namely that the leakage current, which often depends on the applied voltage in non-ohmic fashion, i.e., nonlinear fashion, can be reduced more than proportionally by reducing the cell voltage.

[0023] Figure 2 illustrates a detail from a DRAM memory with dynamic memory cells in accordance with the preferred embodiment of the invention. The selection transistors shown in Figure 1 are represented symbolically in Figure 2 in a simplified manner by means of points at the lines of intersection between the word lines WL and bit lines BL, and the storage capacitor C is represented symbolically by means of a point on the word line. It can be seen that the bit lines are twisted in the center in the case of every second bit line pair BLP.

[0024] A first bit line pair BLP1 has twisted bit lines and a second bit line pair BLP2 has non-twisted bit lines. The advantage of such an arrangement is that a half of the first bit line of the first bit line pair BLP1 is routed adjacent to the first bit line of the second bit line pair BLP2. Equally, a half of the second bit line BL2 of the first bit

line pair BLP1 is routed adjacent to the first bit line of the second bit line pair BLP2. Since instances of signal overcoupling occur between adjacent bit lines, in this way the signal profiles on a half of the first bit line and a half on the second bit line of the first bit line pair BLP1 are coupled into the adjacent first bit line of the second bit line pair, the opposite signal profiles meaning that the coupling-in signals are in opposite directions and reciprocally compensate one another. In this way, it is possible to reduce a coupling-in of a disturbing signal on account of signal profiles between the bit lines of different bit line pairs.

[0025] This is particularly advantageous, in contrast to the prior art, since a symmetrical signal profile can be achieved by means of the dynamic memory cell according to the invention.

[0026] Since the charge of the storage capacitor is applied only to one of the bit lines in the case of conventional memory cells, an asymmetrical signal profile results, so that complete compensation of the overcoupled signals is not achieved in the case of the arrangement shown in Figure 2.

[0027] Figure 3 illustrates a cross section through a semiconductor substrate with two integrated dynamic memory cells according to the invention. The storage capacitor C is embodied as a trench capacitor and formed by an inner region 10 and an outer region 11. The inner region 10 and the outer region 11 are isolated from one another by an insulation layer 12, thus producing a capacitor arrangement. Arranged above the trench capacitor is a word line stack 13, which is electrically connected to a word line 14. In the illustration shown, the word line 14 runs perpendicular to the sectional plane. The word line 14, the word line stack 13 and the trench capacitor 10, 11, 12 are preferably integrated vertically one above the other in the substrate.

[0028] A first selection transistor T1 is arranged vertically on a first side of the word line stack 13. A first conductive region 15, connected to the first bit line BL1,

runs on the first side, i.e., adjacent to the word line 14. The first conductive region 15 is connected to a first drain/source region 16 of the first selection transistor T1. The first drain/source region 16 is preferably n⁺-doped and isolated from the word line stack 13 by a first insulation 17. A first channel region 18 of the first selection transistor T1 is arranged in the vertical direction below the first source/drain region 16. The insulation 17 between the first channel region 18 of the first selection transistor T1 and the word line stack 13 is designed as gate oxide 17.

[0029] A second source/drain region 24, electrically connected to the inner region 10 of the storage capacitor, is situated in the vertical direction below the first channel region 18. A first selection transistor T1 is formed in this way, which transistor can be driven via the word line 14 and can apply the charge in the inner region 10 of the storage capacitor to the first bit line BL1 depending on a selection signal on the word line 14.

[0030] A contact-connection region 19, connected to the second bit line BL2 (not shown), is provided on a second side of the word line stack 13. Via a second conductive region 20, the contact-connection region 19 can be connected to a third source/drain region 21 of the second selection transistor T2. The third source/drain region 21 is isolated from the word line stack 13 by a second insulation 25. A second channel region 26 of the second selection transistor T2 is situated in the vertical direction below the third source/drain region 21.

[0031] The second insulation 25, likewise designed as gate oxide, runs between the word line stack 13 and the second channel region 26 of the second selection transistor T2. A fourth source/drain region 22, likewise isolated from the word line stack 13 by the second insulation 25, is situated in the vertical direction below the second channel region 26.

[0032] The fourth source/drain region 22 is situated in the region of the trench capacitor, but an insulation region 23 is arranged between the inner region 10 of the

trench capacitor and the fourth source/drain region 22. Instead, the fourth source/drain region 22 is electrically connected to the outer region 11 of the trench capacitor. In this way, the outer region 11 of the trench capacitor C is contact-connected via the second selection transistor T2. If the second selection transistor T2 is activated under the control of the selection signal on the word line 14, then the outer region 11 of the trench capacitor is connected to the second bit line BL2 via the contact region 19.

[0033] This produces a structure in which the selection transistors T1, T2 are arranged vertically, so that the area requirement is not expected to be enlarged in the realization of such a memory cell according to the invention.

[0034] Figure 4 illustrates a plan view of a substrate with integrated dynamic memory cells according to the invention. For the sake of clarity, the vertically running word lines and the horizontally running bit lines are not shown. The memory cells are represented in the form of small square boxes with elliptical selection transistors T1, T2 connected on both sides. The sectional illustration of Figure 3 corresponds to a section line depicted in dashed fashion in Figure 4.

[0035] In order that the memory cells are in contact with both bit lines, the first and second conductive regions 15, 20 are provided, the first conductive regions 15 in each case being connected to a first selection transistor and the second conductive regions 20 in each case being connected to a second selection transistor T2.

[0036] The conductive regions 15, 20 are provided in a length such that, with the aid of contact connections, the first conductive region 15 can be connected to the first bit line BL1 and the second conductive region 20 can be connected to the second bit line BL2. The bit lines (not shown in Figure 4) run horizontally over the structures illustrated in such a way that the first bit line runs over the contact connections 19 of the first conductive regions 15 and the second bit line runs over

the contact connections 19 of the second conductive regions 20. The word lines 14 run at right angles with respect thereto, to be precise in each case over the memory cell structure, in order to make contact with the word line stack 13.

[0037] In this way, it is possible to produce an improved DRAM memory circuit which manages without an increased area requirement and, with the aid of two selection transistors T1, T2, simultaneously connects a storage capacitor C to two adjacent bit lines.

[0038] This has the advantage that the signal profiles on the adjacent bit lines of a bit line pair are symmetrical, so that, in the case of twisted bit lines, the crosstalk on the bit line which is not twisted with respect thereto leads to coupled-in signals which reciprocally compensate one another.